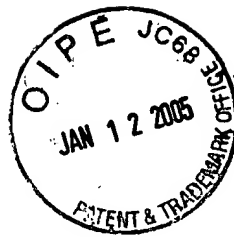


00839.000449



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

| | | |
|-----------------------------|---|--------------------------|
| In re Application of: |) | |
| | : | Examiner: Erik J. Kielin |
| ATSUSHI KOIKE, ET AL. |) | |
| | : | Group Art Unit: 2813 |
| Application No.: 09/982,846 |) | |
| | : | |
| Filed: October 22, 2001 |) | |
| | : | |
| For: METHOD FOR FORMING |) | |
| A DEPOSITED FILM BY | : | |
| PLASMA CHEMICAL VAPOR |) | |
| DEPOSITION | : | January 11, 2005 |

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Sir:

a) Introductory Comments

In response to the outstanding final Official Action dated October 12, 2004,
kindly amend the subject application and consider the following remarks.